

Dektak XT Contact Profilometer

- Measure **thickness, step height and morphology of films and structures**
- Stylus Force: 1 to 15mg
- Stylus radius: 12.5um
- Maximum Scan Length: 50 mm
- Max. Wafer Size 150 mm
- Maximum step height: 1 mm.
- Vertical resolution: 0.1 nm.

